

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A piezoelectric/electrostrictive film type actuator which comprises comprising:

a ceramic substrate comprising a plurality of laminated thin plate layers and having a cavity formed in an internal portion thereof; and

a piezoelectric/electrostrictive device disposed on the one surface of said ceramic substrate and including a plurality of piezoelectric/electrostrictive film films and electrode film films; and which is driven by displacement of the piezoelectric/electrostrictive device,

characterized in that the piezoelectric/electrostrictive device wherein the said piezoelectric/electrostrictive film films and said electrode film films are alternately laminated to form such that the electrode film from an films form uppermost layer and a lowermost layer layers of said piezoelectric/electrostrictive device possesses a plurality of layers of piezoelectric/electrostrictive films.; and

wherein said actuator is driven by displacement of said piezoelectric/electrostrictive device such that said cavity is pressurized by deforming a part of a wall thereof with said piezoelectric/electrostrictive device.

2. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 1, wherein the said piezoelectric/electrostrictive device possesses includes two to four layers of said piezoelectric/electrostrictive films.

3. (Currently Amended) A piezoelectric/electrostrictive film type actuator comprising:

a ceramic substrate; and

a piezoelectric/electrostrictive device disposed on said ceramic substrate and

including a plurality of piezoelectric/electrostrictive films and electrode films;
wherein said piezoelectric/electrostrictive films and said electrode films are
alternately laminated such that electrode films form uppermost and lowermost layers
of said piezoelectric/electrostrictive device; The piezoelectric/electrostrictive film type
actuator according to claim 1,

wherein a thickness t_n of an n-th piezoelectric/electrostrictive film from the
bottom in the of said piezoelectric/electrostrictive device satisfies the following
equation: $t_n \leq t_{n-1} \times 0.95$; and

wherein said actuator is driven by displacement of said piezoelectric/
electrostrictive device.

4. (Currently Amended) The piezoelectric/electrostrictive film type actuator
according to claim 1, wherein a per layer thickness per layer of the said
piezoelectric/electrostrictive filmfilms is $30 \mu\text{m}$ or less.

5. (Currently Amended) The piezoelectric/electrostrictive film type actuator
according to claim 1, wherein at least one layer of the said piezoelectric/
electrostrictive films is formed by an electrophoresis deposition method.

6. (Currently Amended) The piezoelectric/electrostrictive film type actuator
according to claim 1, wherein comprising two or more of said piezoelectric/
electrostrictive devices are arranged disposed on the said same ceramic substrate.

7. (Cancelled).

8. (Currently Amended) The piezoelectric/electrostrictive film type actuator
according to claim 71, wherein the said ceramic substrate is constituted of comprises
two or three laminated thin plate layers of thin plates.

9. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 71, wherein a thickness of a thinner portion of the said ceramic substrate is 50 μm or less.

10. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 1, wherein the said ceramic substrate is ~~formed of~~comprises a material selected from the group consisting of materials containing any of zirconium oxide, aluminum oxide, magnesium oxide, aluminum nitride, and silicon nitride as a major component.

11. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 1, wherein the said ceramic substrate is ~~formed of~~comprises a material containing either partially stabilized zirconium oxide or completely stabilized zirconium oxide ~~which is as~~ a major component.

12. (Currently Amended) An ink pump of a printer head disposed in an ink jet printer ~~The comprising the~~ piezoelectric/electrostrictive film type actuator according to claim 1, which is used as ~~an ink pump of a printer head disposed in an ink jet printer~~.

13. (Currently Amended) A piezoelectric/electrostrictive film type actuator ~~which comprises~~comprising:

a ceramic substrate having a cavity formed in an internal portion thereof; and
a piezoelectric/electrostrictive device disposed on the one surface of said
ceramic substrate and including a plurality of piezoelectric/electrostrictive filmfilms
~~and electrode film~~films~~, and said substrate being provided with a cavity being formed~~
~~in an internal portion thereof and~~

wherein ~~said cavity being~~is pressurized by deforming a part of a wall of the
~~cavity~~thereof with the said piezoelectric/electrostrictive device; and

characterized in that the wherein said piezoelectric/electrostrictive film type actuator is formed prepared by a method comprising the steps of:

preparing a green sheet laminate including at least one green sheet which is as a substrate and one or a plurality of more green sheets in which each having at least one hole portion is formed therein; and

sintering the said green sheet laminate to obtain a ceramic laminate;

forming an electrode film (A) in the on an outer surface of the obtained said ceramic laminate by a first film forming method;

thereafter forming a piezoelectric/electrostrictive film (A) on the said electrode film (A) by a second film forming method; ; further

forming an electrode film (B) on the said piezoelectric/electrostrictive film (A) by the said first film forming method, and;

repeating the steps of forming of the said piezoelectric/electrostrictive film (A) and electrode film (B) onee or a plurality of one or more times;

thereafter forming a piezoelectric/electrostrictive film (B) on the said electrode film (B) by the said second film forming method, ;and further

forming an electrode film (C) on the said piezoelectric/electrostrictive film (B) by the said first film forming method; and

sintering the said piezoelectric/electrostrictive filmfilms and/or the said electrode filmfilms a predetermined number of times at an arbitrary timing times during a period after between the said step of forming said electrode film (A) is formed until and said step of forming the said electrode film (C) is formed.

14. (Currently Amended) A piezoelectric/electrostrictive film type actuator comprising:

a ceramic substrate having a cavity formed in an internal portion thereof; and
a piezoelectric/electrostrictive device disposed on said ceramic substrate and including a plurality of piezoelectric/electrostrictive films and electrode films;

wherein said cavity is pressurized by deforming a part of a wall thereof with said piezoelectric/electrostrictive device; and

wherein said piezoelectric/electrostrictive film type actuator is formed by a method comprising the steps of:

preparing a green sheet laminate including at least one green sheet as a substrate and one or more green sheets each having at least one hole portion formed therein;

sintering said green sheet laminate to obtain a ceramic laminate;
forming an electrode film (A) on an outer surface of said ceramic laminate by a first film forming method;

forming a piezoelectric/electrostrictive film (A) on said electrode film (A) by a second film forming method;

forming an electrode film (B) on said piezoelectric/electrostrictive film (A) by said first film forming method;

repeating the steps of forming said piezoelectric/electrostrictive film (A) and electrode film (B) one or more times;

forming a piezoelectric/electrostrictive film (B) on said electrode film (B) by said second film forming method;

forming an electrode film (C) on said piezoelectric/electrostrictive film (B) by said first film forming method; and

sintering said piezoelectric/electrostrictive films and/or said electrode films a predetermined number of times at arbitrary times between said step of forming said electrode film (A) and said step of forming said electrode film (C); The piezoelectric/electrostrictive film type actuator according to claim 13, wherein a thickness t_n of the an n-th piezoelectric/electrostrictive film formed n-th time satisfies the following equation: $t_n \leq t_{n-1} \times 0.95$.

15. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 13, wherein in the step said step of forming said electrode film (B) and includes sintering the said electrode film (B) at a sintering temperature of $Tm1$ ($^{\circ}C$), and wherein said step of forming said piezoelectric/electrostrictive film (B) and includes sintering the said piezoelectric/ electrostrictive film (B) at a sintering

temperature of Tm2 (°C), such that the following equation is satisfied:

$$0 \leq Tm2 - Tm1 \leq 300.$$

16. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 13, wherein ~~the said first and said second film forming methods each comprise at least one of piezoelectric/electrostrictive film and electrode film are subjected to a plurality of film forming methods per layer and, such that each of said electrode films and each of said piezoelectric/electrostrictive films are formed by the same or a different film forming method.~~

17. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 13, wherein ~~as the said first and said second film forming methods each comprise~~, at least one thick film forming method selected from a ~~the group consisting of a screen printing method, dipping method, coating method, and electrophoresis deposition method is used~~.

18. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 13, wherein ~~as the said second film forming method of the piezoelectric/electrostrictive film, comprises the screen printing method is used to form a first piezoelectric/electrostrictive film time, and the electrophoresis deposition method is used to form second and subsequent piezoelectric/electrostrictive film times.~~

19. (Currently Amended) The piezoelectric/electrostrictive film type actuator according to claim 13, wherein ~~said step of forming said green sheet laminate comprises laminating two or three green sheets in each of which having at least one hole portion is formed are laminated therein.~~

20. (Currently Amended) ~~An ink pump of a printer head disposed in an ink jet printer comprising the~~ The piezoelectric/electrostrictive film type actuator according to claim 13, ~~which is used as an ink pump of a printer head disposed in an ink jet printer.~~

21. (Currently Amended) A manufacturing method of manufacturing a piezoelectric/electrostrictive film type actuator which comprises comprising a ceramic substrate having a cavity formed in an internal portion thereof, and a piezoelectric/electrostrictive device disposed on the one surface of said ceramic substrate and including a plurality of piezoelectric/electrostrictive filmfilms and electrode filmfilms, and said substrate being provided with a cavity being formed in an internal portion thereof and wherein said cavity being is pressurized by deforming a part of a wall thereof the cavity with the said piezoelectric/electrostrictive device,

characterized in that the said method comprisescomprising the steps of:

A) a step A of preparing a green sheet laminate including at least one green sheet which isas a substrate and at least one green sheet in whichhaving at least one hole portion formed therein is formed and sintering the said green sheet laminate to obtain a ceramic laminate;

B) a step B of forming an electrode film (A) in on the an outer surface of the said obtained ceramic laminate by a first film forming method;

C) a step C of forming a piezoelectric/electrostrictive film (A) on the said electrode film (A) by the a second film forming method; and

D) a step D of further forming an electrode film (B) on the said piezoelectric/ electrostrictive film (A) by the said first film forming method to;

E) repeating the steps C and D once or a plurality of one or more times; and

F) a step E of thereafter forming a piezoelectric/electrostrictive film (B) on the said electrode film (B) by the said second film forming method; and

G) and further a step F of forming an electrode film (C) on the said piezoelectric/ electrostrictive film (B) by the said first film forming method; and

wherein sintering of thesaid piezoelectric/electrostrictive filmfilms

and/or the said electrode film films is performed are sintered a predetermined number of times at an arbitrary timing during a period times between after the said electrode film (A) is formed in step B until the and said electrode film (C) is formed in step G.

22. (Currently Amended) The manufacturing method of the piezoelectric/electrostrictive film type actuator according to claim 21, A method of manufacturing a piezoelectric/electrostrictive film type actuator comprising a ceramic substrate having a cavity formed in an internal portion thereof, and a piezoelectric/electrostrictive device disposed on said ceramic substrate and including a plurality of piezoelectric/electrostrictive films and electrode films, wherein said cavity is pressurized by deforming a part of a wall thereof with said piezoelectric/electrostrictive device, said method comprising the steps of:

- A) preparing a green sheet laminate including at least one green sheet as a substrate and at least one green sheet having at least one hole portion formed therein and sintering said green sheet laminate to obtain a ceramic laminate;
- B) forming an electrode film (A) on an outer surface of said ceramic laminate by a first film forming method;
- C) forming a piezoelectric/electrostrictive film (A) on said electrode film (A) by a second film forming method;
- D) forming an electrode film (B) on said piezoelectric/electrostrictive film (A) by said first film forming method;
- E) repeating steps C and D one or more times;
- F) forming a piezoelectric/electrostrictive film (B) on said electrode film (B) by said second film forming method; and
- G) forming an electrode film (C) on said piezoelectric/electrostrictive film (B) by said first film forming method;
wherein said piezoelectric/electrostrictive films and/or said electrode films are sintered a predetermined number of times at arbitrary times between

said electrode film (A) is formed in step B and said electrode film (C) is formed in step G; and

wherein a thickness t_n of ~~the~~ an n-th piezoelectric/ electrostrictive film ~~formed~~ ~~n-th time~~ satisfies the following equation: $t_n \leq t_{n-1} \times 0.95$.

23. (Currently Amended) The manufacturing method of the piezoelectric/ electrostrictive film type actuator according to claim 21, wherein ~~in the steps of forming and~~ said step D includes sintering the said electrode film (B) at a sintering temperature of Tm_1 ($^{\circ}$ C), and wherein said step E and forming and includes sintering the said piezoelectric/electrostrictive film (B) at a sintering temperature of Tm_2 ($^{\circ}$ C), such that the following equation is satisfied: $0 \leq Tm_2 - Tm_1 \leq 300$.

24. (Currently Amended) The manufacturing method of the piezoelectric/ electrostrictive film type actuator according to claim 21, ~~further comprising the steps of:~~ subjecting the wherein said first film and said second forming methods each comprise at least one of a plurality of film forming methods such that each of said electrode films and each of said piezoelectric/electrostrictive film and electrode film to films are a plurality of film forming methods per layer to form the films formed by the same or a different film forming method in the respective steps.

25. (Currently Amended) The manufacturing method of the piezoelectric/ electrostrictive film type actuator according to claim 21, wherein said first and said second film forming methods each comprise at least one thick film forming method selected from ~~a~~ the group consisting of a screen printing method, dipping method, coating method, and electrophoresis deposition method is used as the film forming method.

26. (Currently Amended) The manufacturing method of the piezoelectric/ electrostrictive film type actuator according to claim 21, wherein as the said second film forming method of the piezoelectric/electrostrictive film, comprises the screen

~~printing method is used to form a first time piezoelectric/electrostrictive film and the electrophoresis deposition method is used to form second and subsequent piezoelectric/electrostrictive filmstimes.~~

27. (Currently Amended) The manufacturing method of the piezoelectric/electrostrictive film type actuator according to claim 21, wherein the step A includes a step of preparing each of said at least one or a plurality of laminated green sheets of step A which that form the said substrate and in each of which have at least one hole portion is formed therein.

28. (Currently Amended) The manufacturing method of the piezoelectric/electrostrictive film type actuator according to claim 27, further comprising the steps of: wherein said at least one laminated green sheetlaminating comprises two or three laminated green sheets in each of which at least one hole portion is formed.

29. (Currently Amended) The manufacturing method of the piezoelectric/electrostrictive film type actuator according to claim 21, wherein the actuator is used as an An ink pump of a printer head disposed in an ink jet printer comprising an actuator formed according to the method of claim 21.

30. (New) The method according to claim 16, wherein said first and said second film forming methods are the same.

31. (New) The method according to claim 24, wherein said first and said second film forming methods are the same.